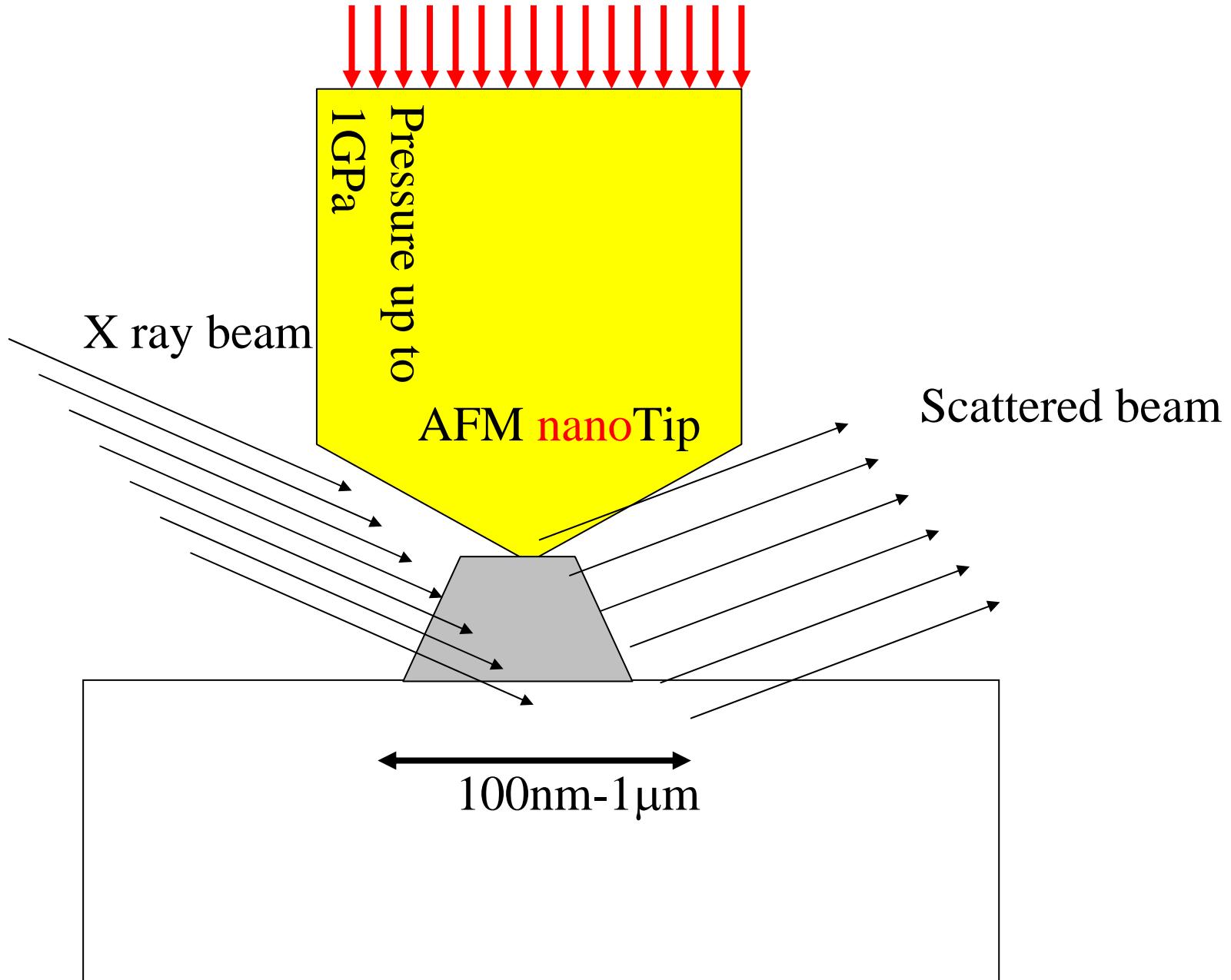


# **Combination of Atomic Force Microscopy and X ray beam : experimental set up and objectives**

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Nanotribology  
tip surface interaction

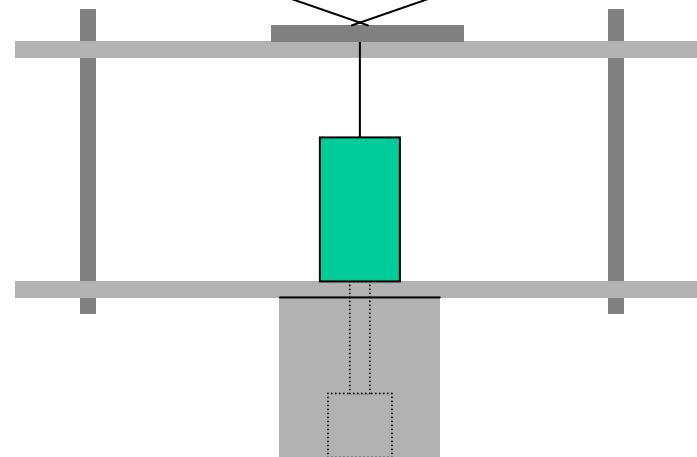


X ray and tip:

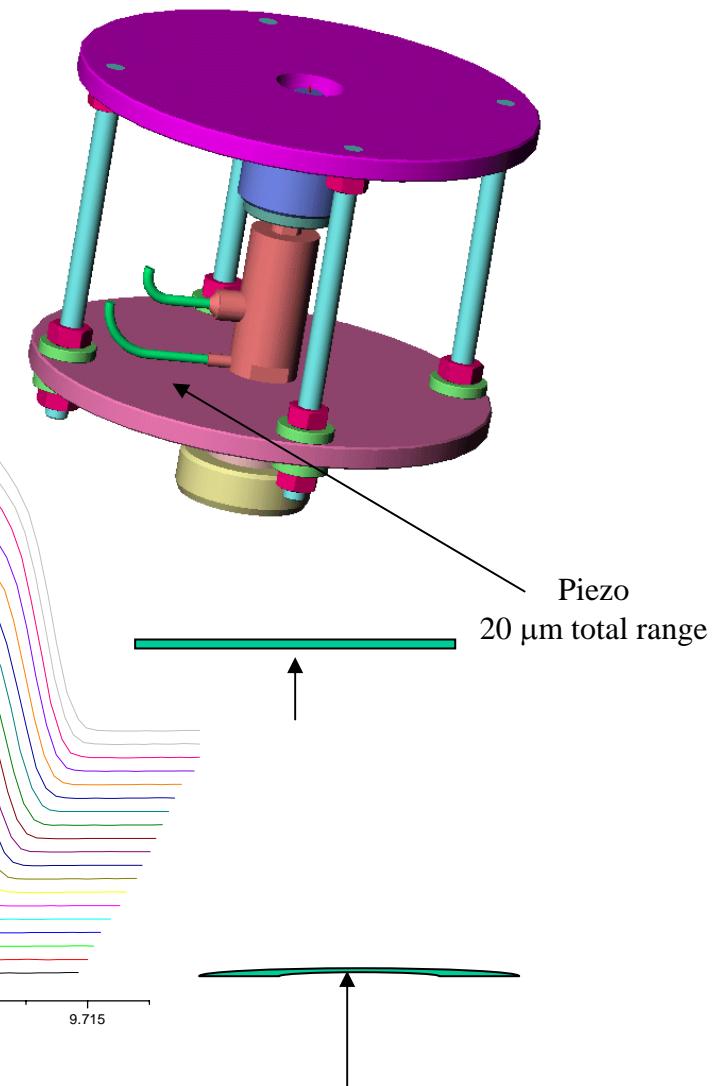
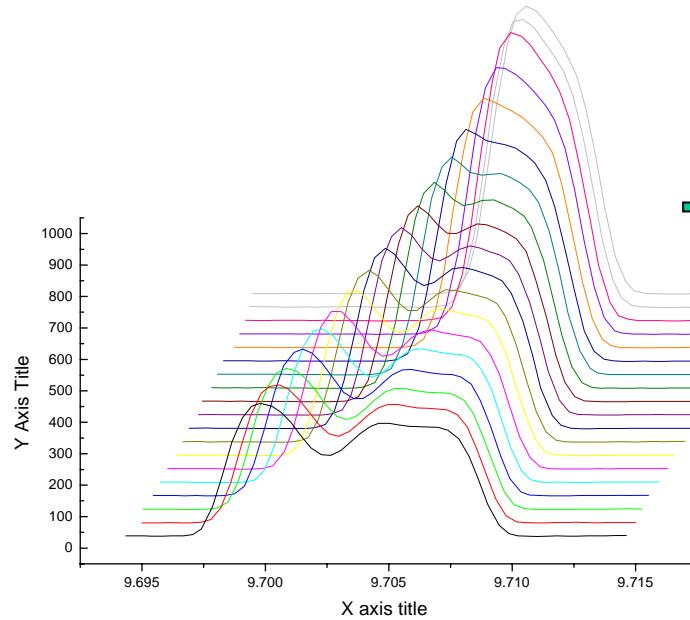
first exercise....

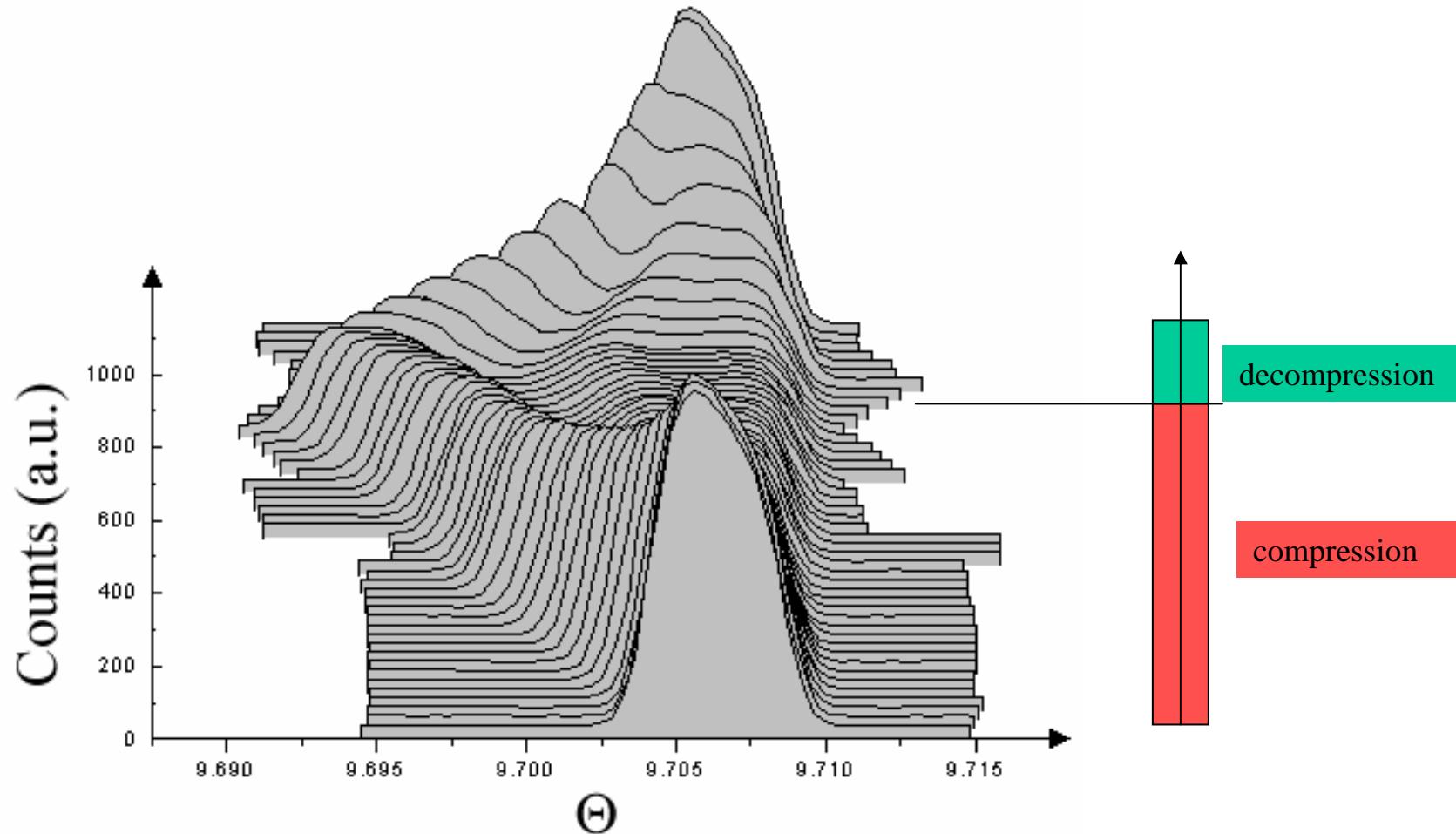
## Designed of a very simple machine (2002)

combining surface pressure (not local enough, poor control)  
and X ray diffraction/topography (D19 coll. J Hartwig/J. Baruchel)



Bragg peak change  
during pushing  
on a 300  $\mu\text{m}$   
thick Si wafer



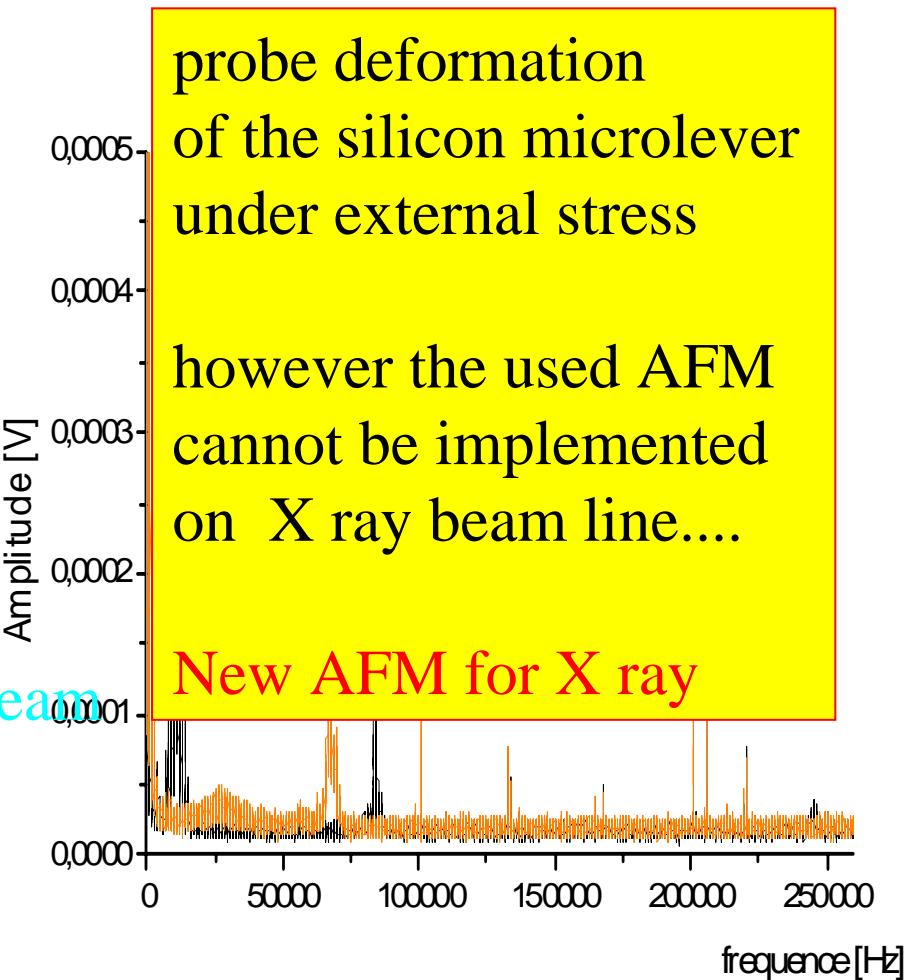
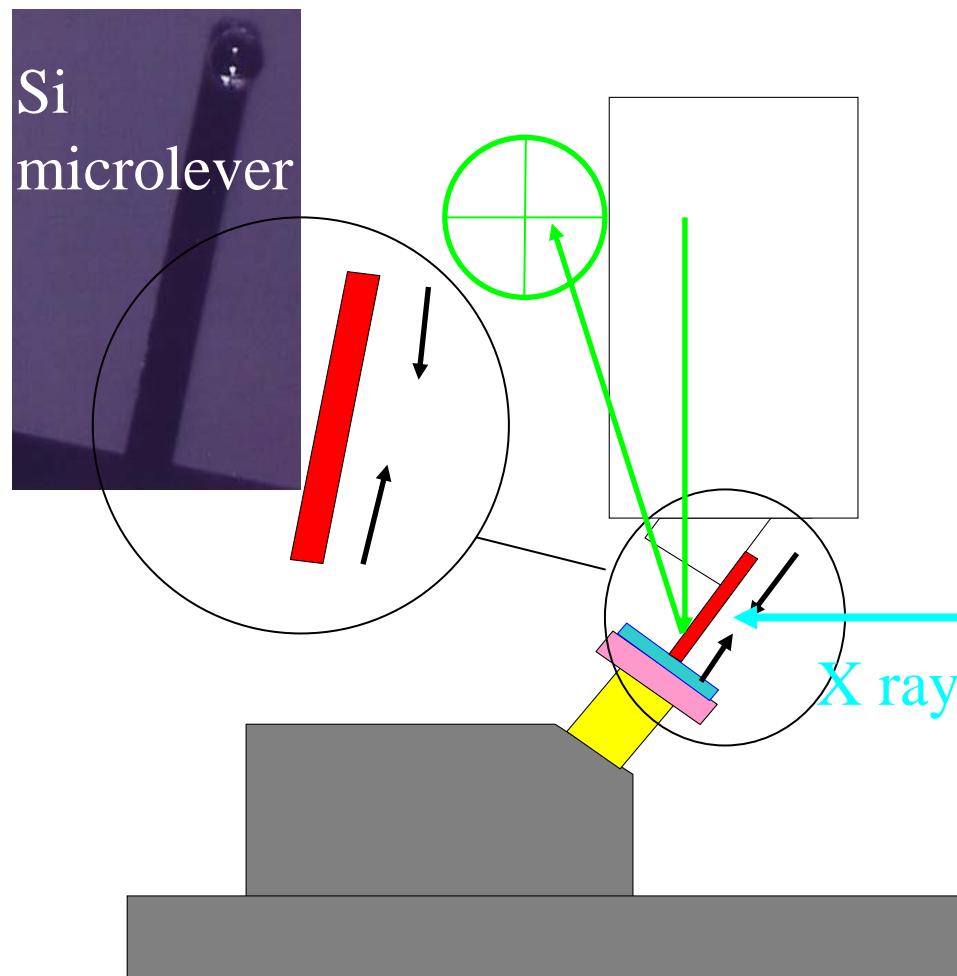


Direct contact

Pulling: adhesion

Pushing: pressure

## test of AFM deformation of a MEMS: mechanical Euler instability

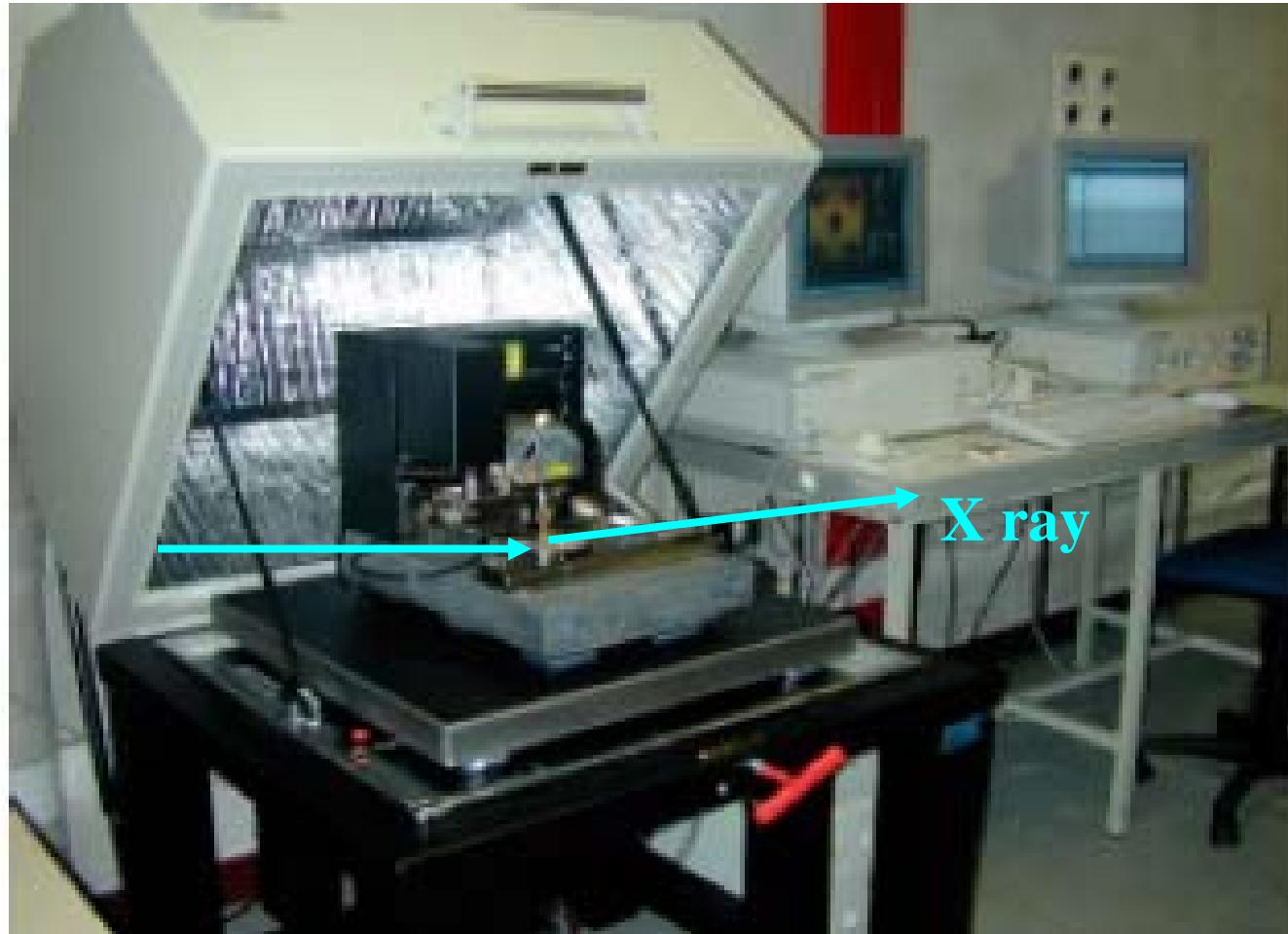


Brownian motion:  
Vibrational characteristics changed by applied stress

X ray and tip:

but....

# Implementation of current AFM on beamline not easy....



X ray and tip: some interests....

1-Mechanics: deformation and structure

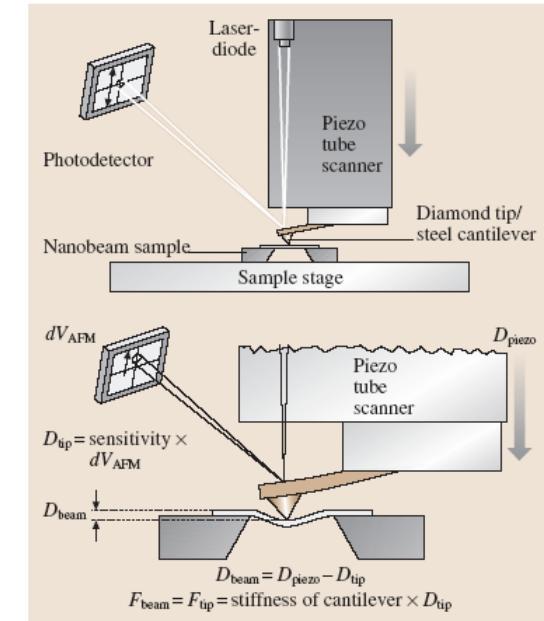
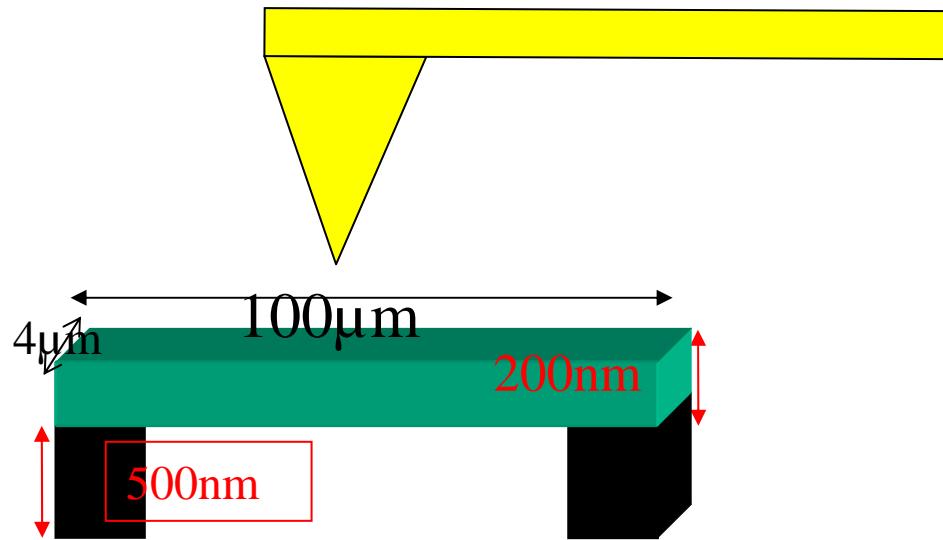
2-Local detection of X ray induced charge

3-Positioning of nanoobjects

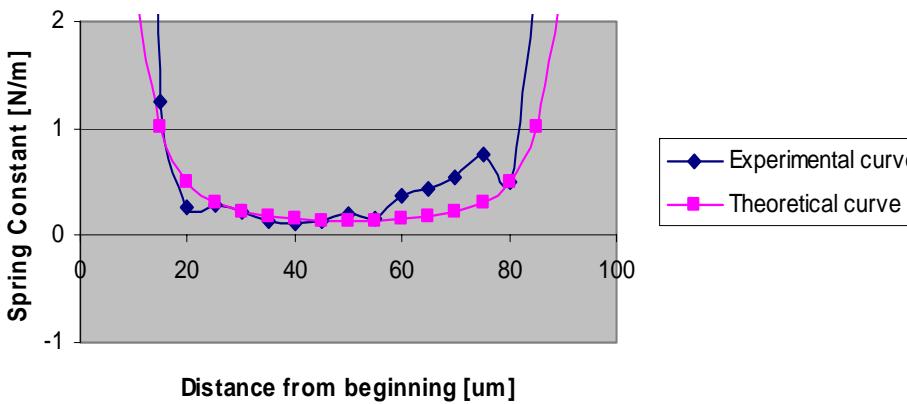
*4-mechanical effect of X ray....2 hbar k*

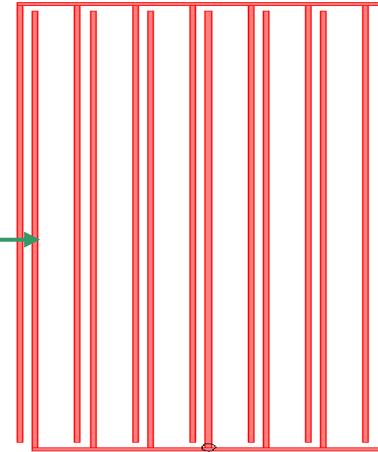
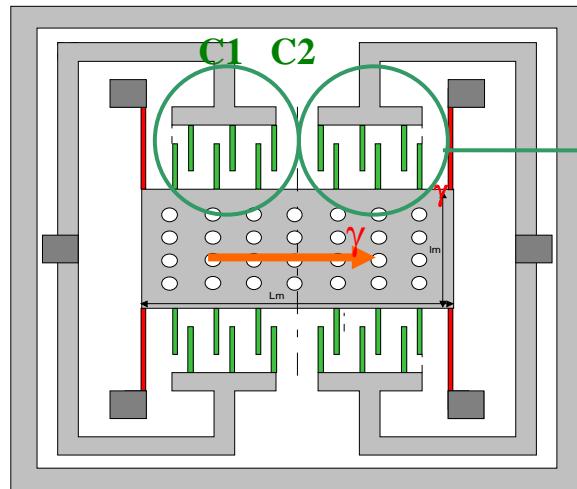
Few photons but large k...

## Estimation of the spring constant of a double fixed micro-beam



## Spring constant measurement

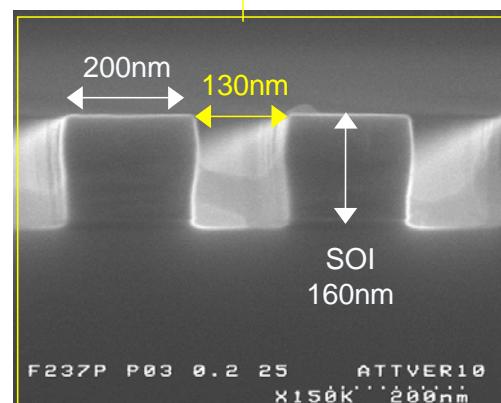
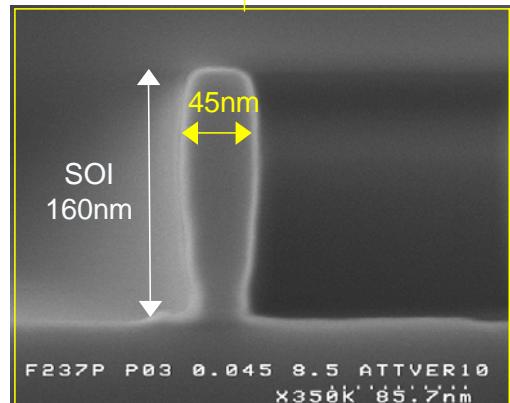
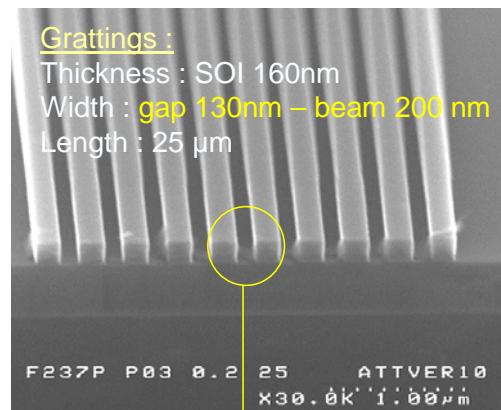
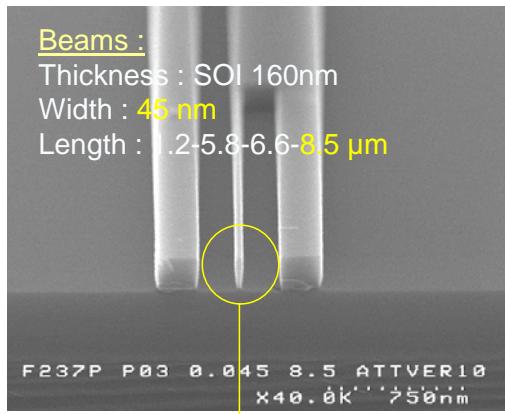




Nano accelerometer

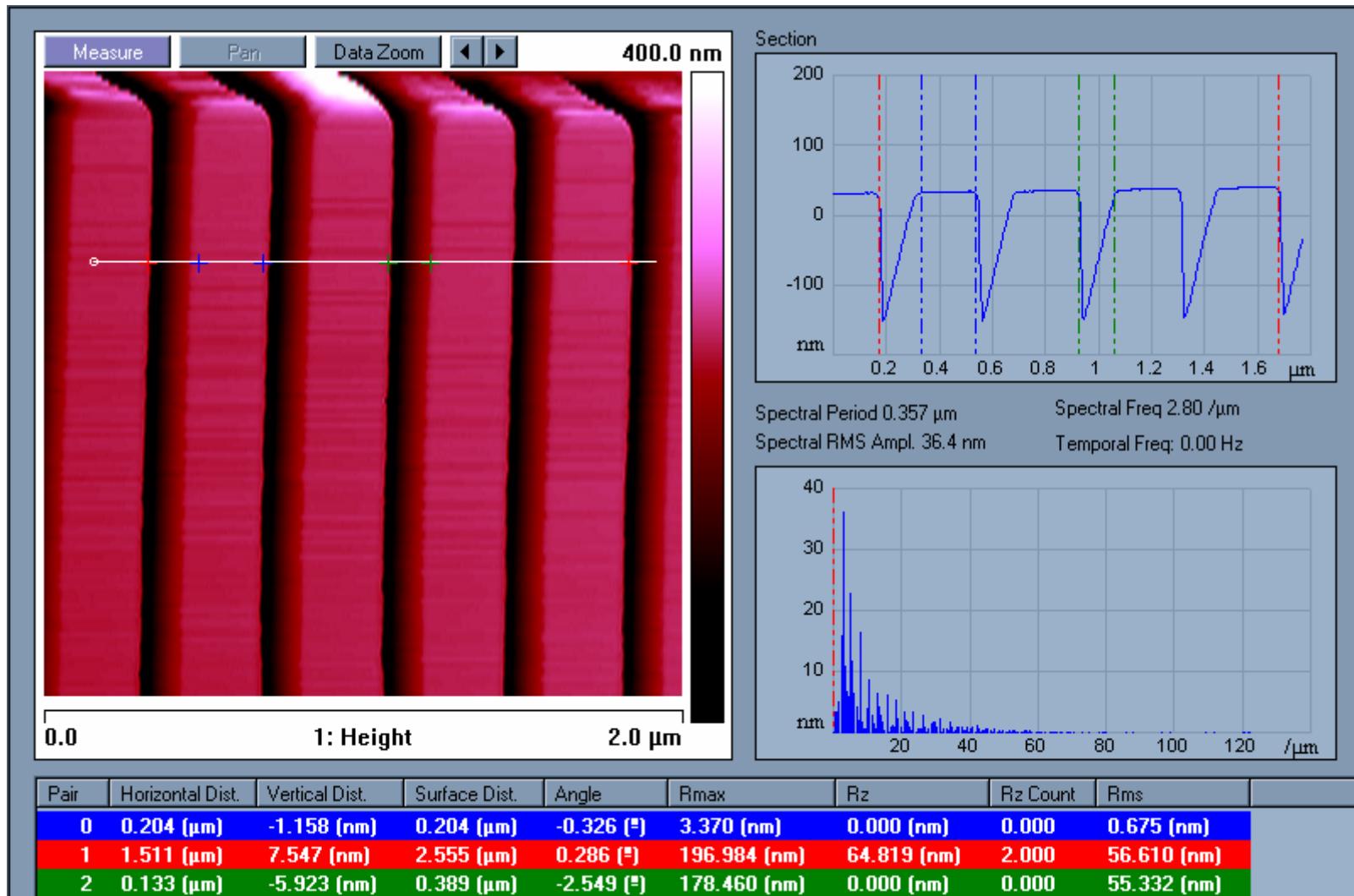
Size nano << optical wavelength

diffraction of light

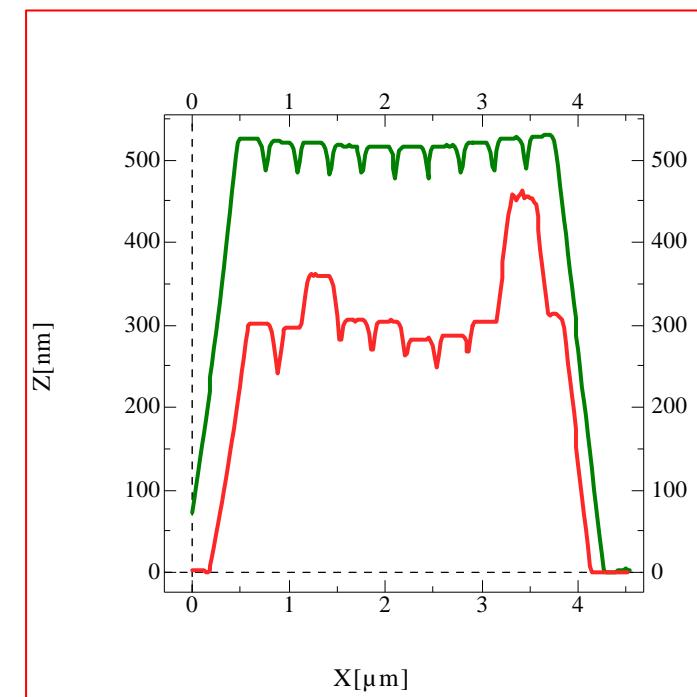
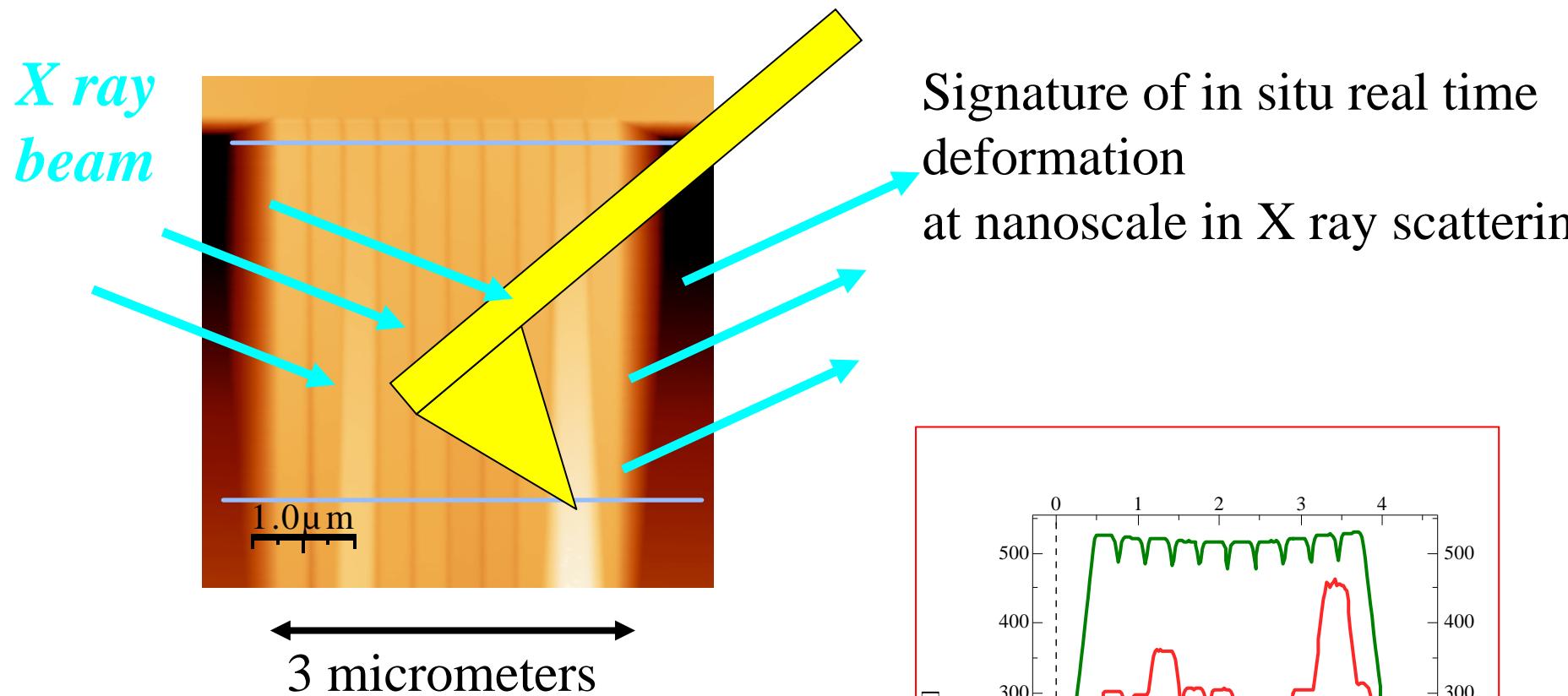


Images MEB  
LETI CEA Grenoble

# AFM imaging of NEMS: true nanostructure coll. ESRF-LEPES-LETI Grenoble



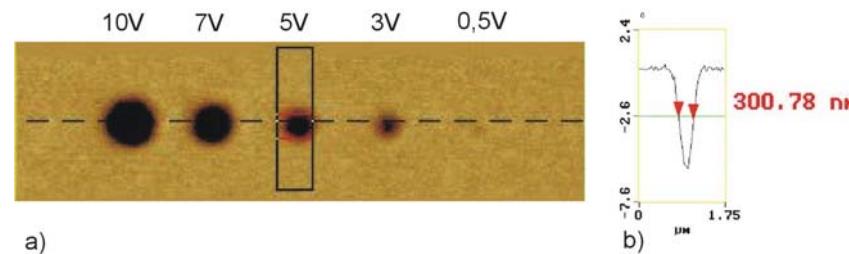
## Deformation of NEMS: nano-electro-mechanical-system



AFM Charge detection by force

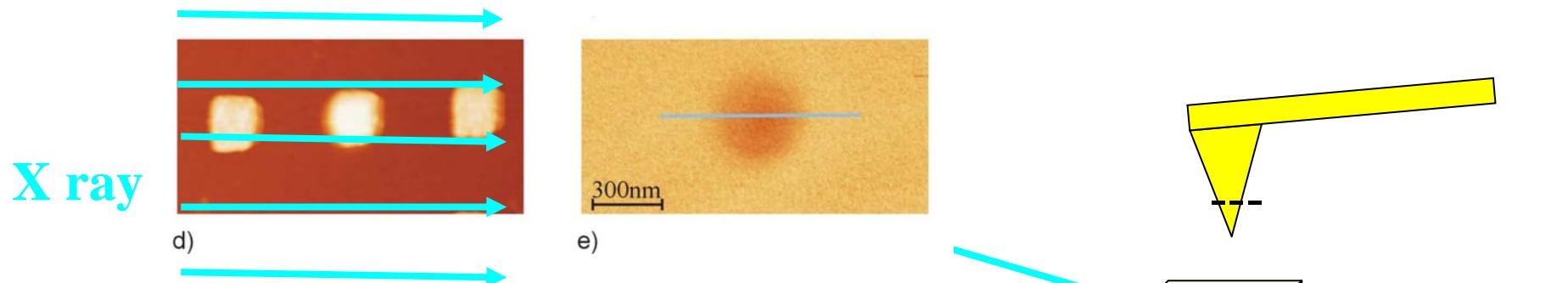
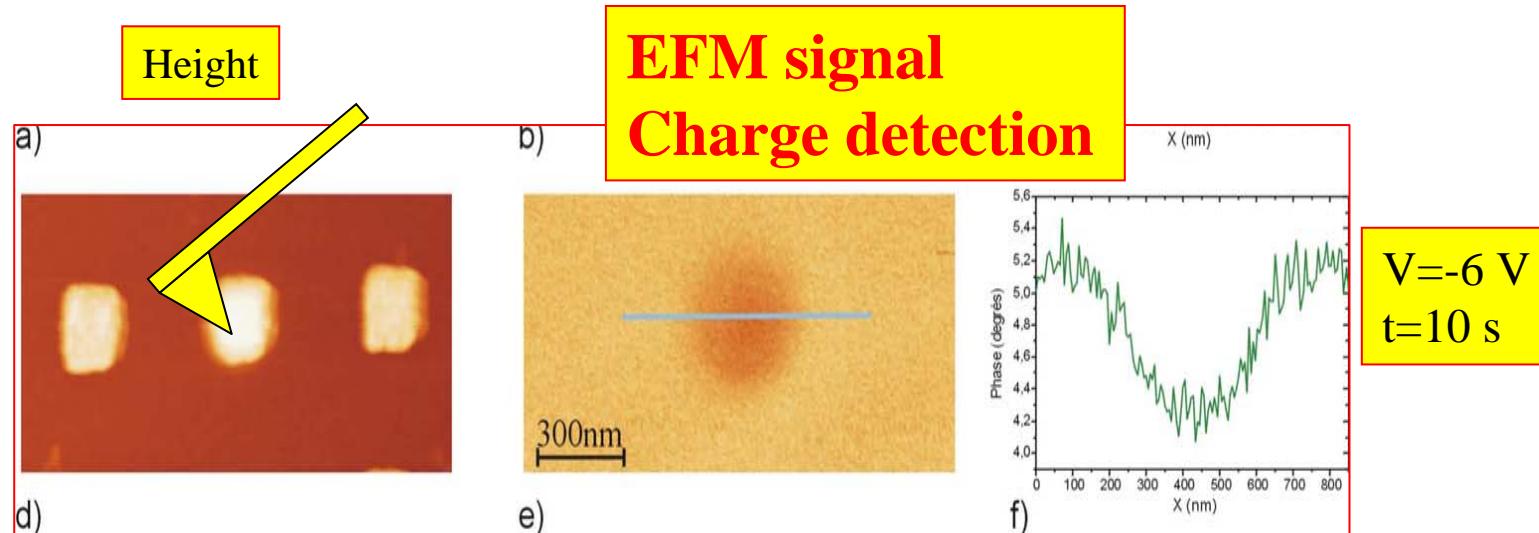
easily down to a few electrons!!!

## EFM Detection of 20-40 électrons in dry air at RT in semiconductor nanostructures



Charging experiments on 7 nm  $\text{SiO}_2$   
(injection time: 10 s)

## Ge dots on silicon wafer: charge tip injected by contact



Detection of charge induced by X ray in Ge dots  
at Ge absorption edge (see Ishi work)  
Electrostatic Force Microscopy

Then thanks to AFM/X ray combination, you can try:

- to locally deform a single object and to probe it by X ray scattering  
*in situ and real time*
- to detect charges induced by X ray ionization (semiconductor)
- to put little sample in the beam to study it: nanomanipulation

BUT...

Implementation of current AFM on beamline not  
easy....but can be done

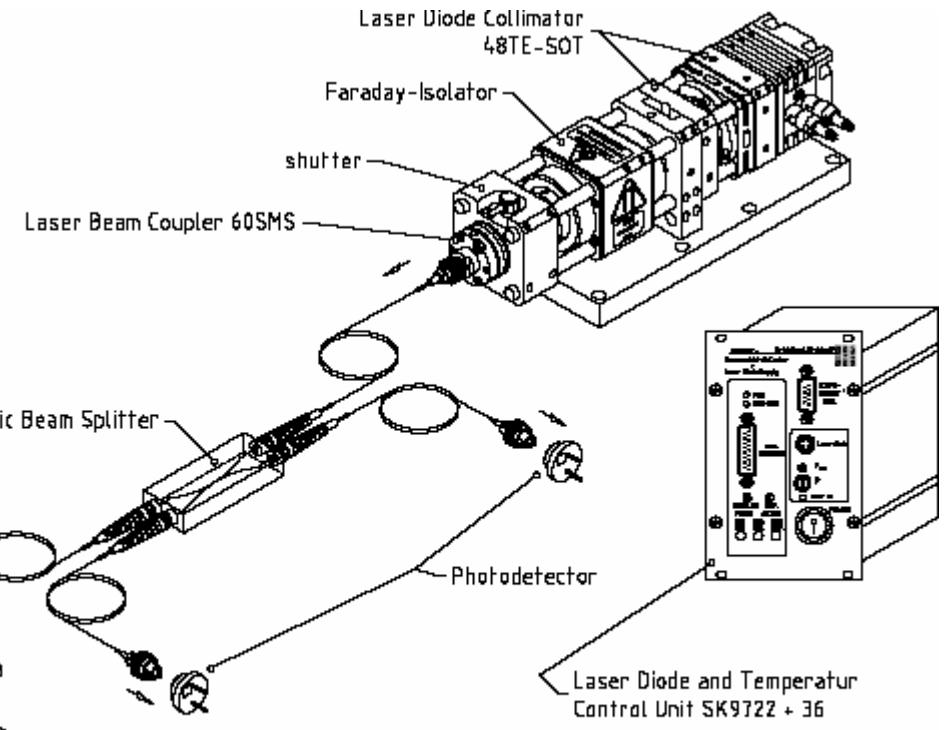
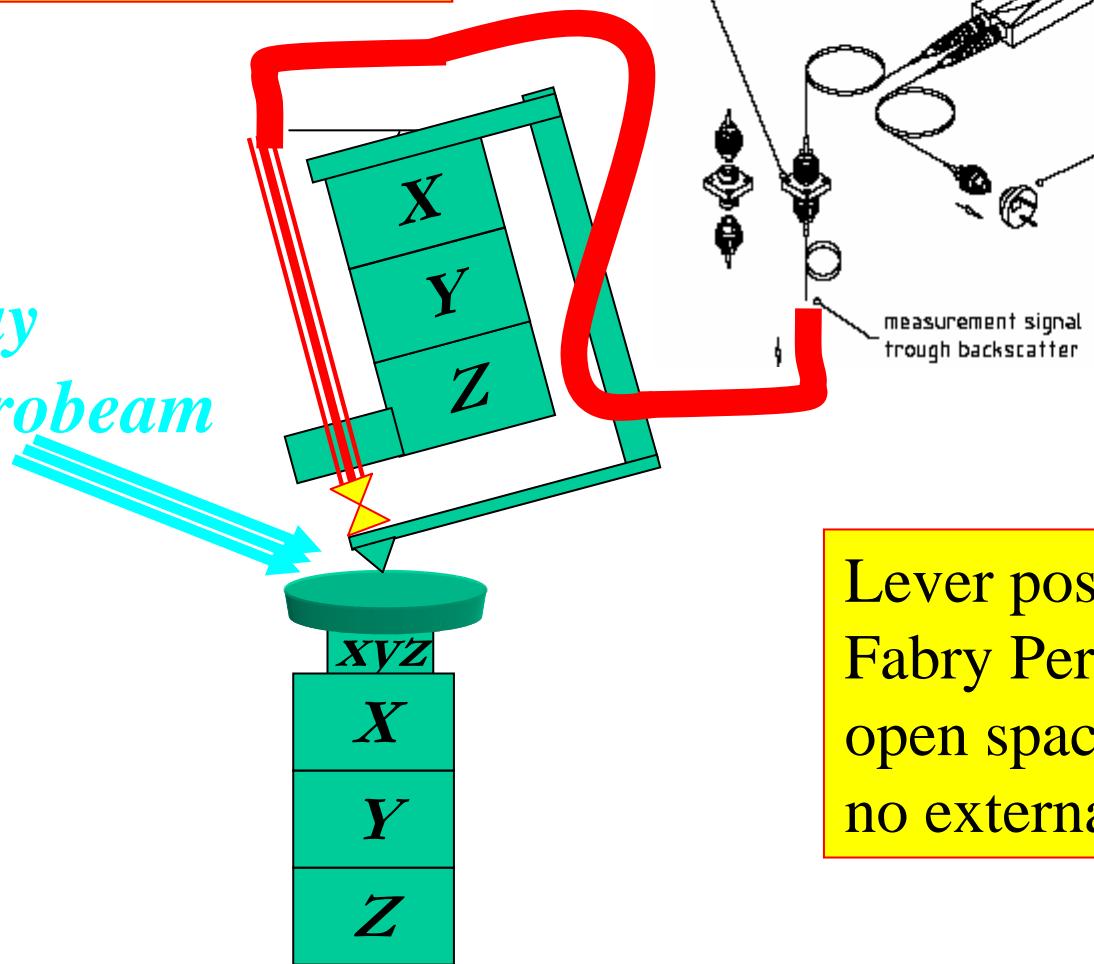


See Olivier Dhez talk already for current detection....

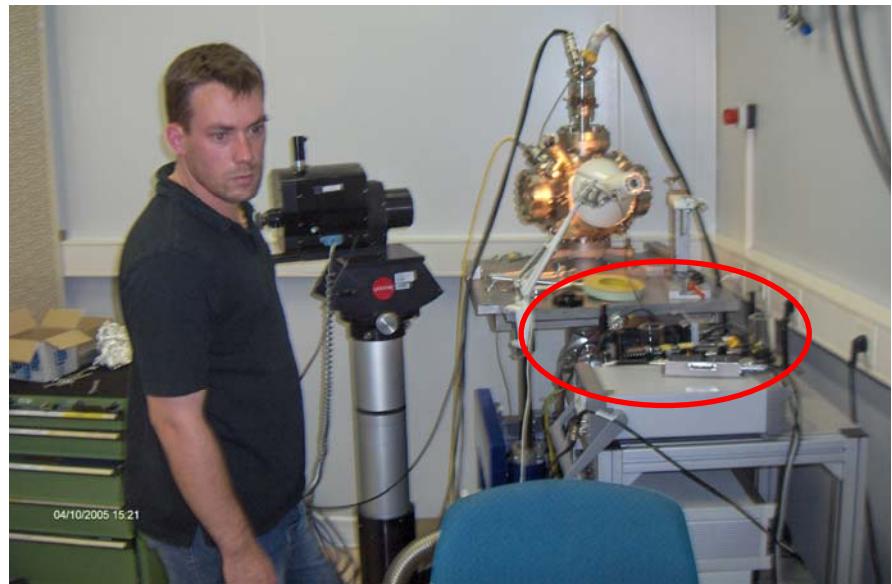
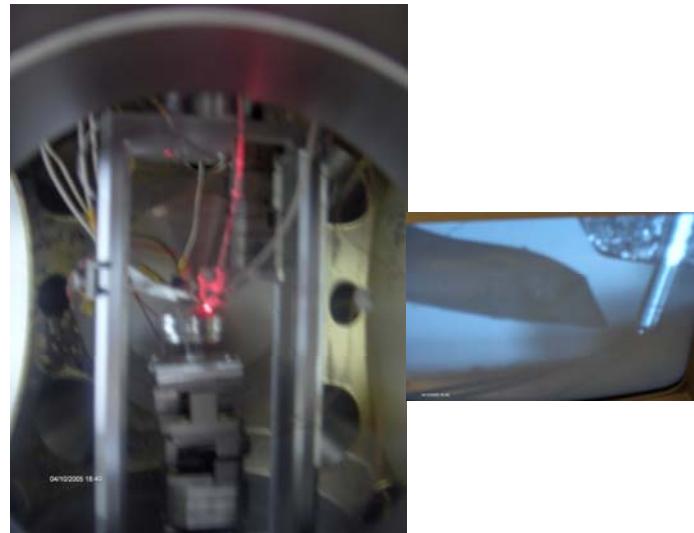
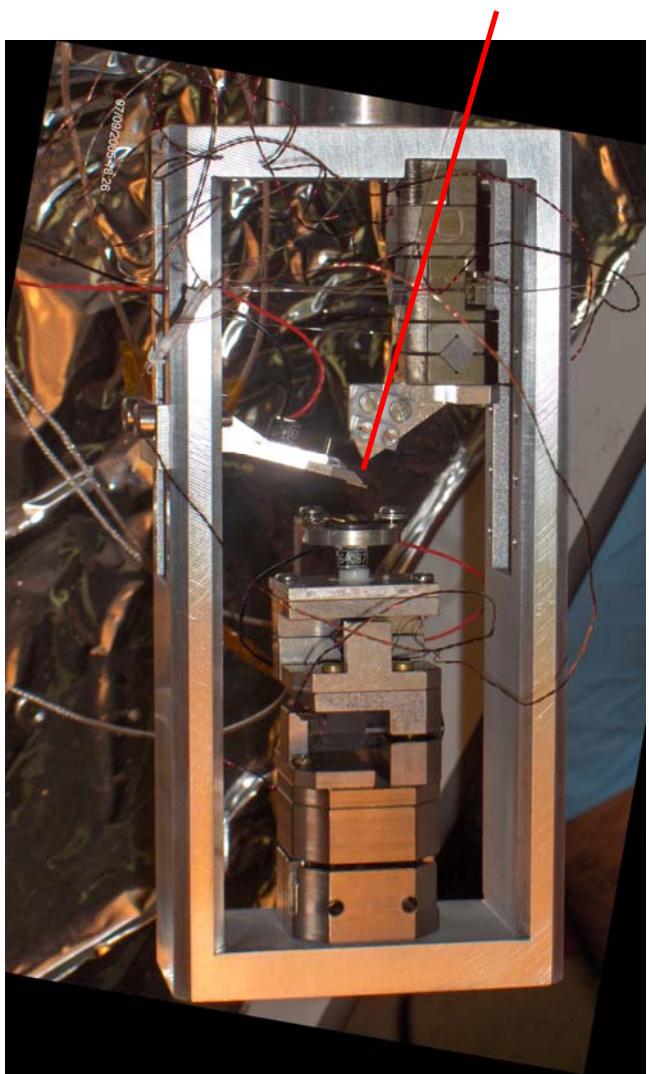
Fabry P  rot cavity:  
combination X ray  
force detection  
nanopositioning

....

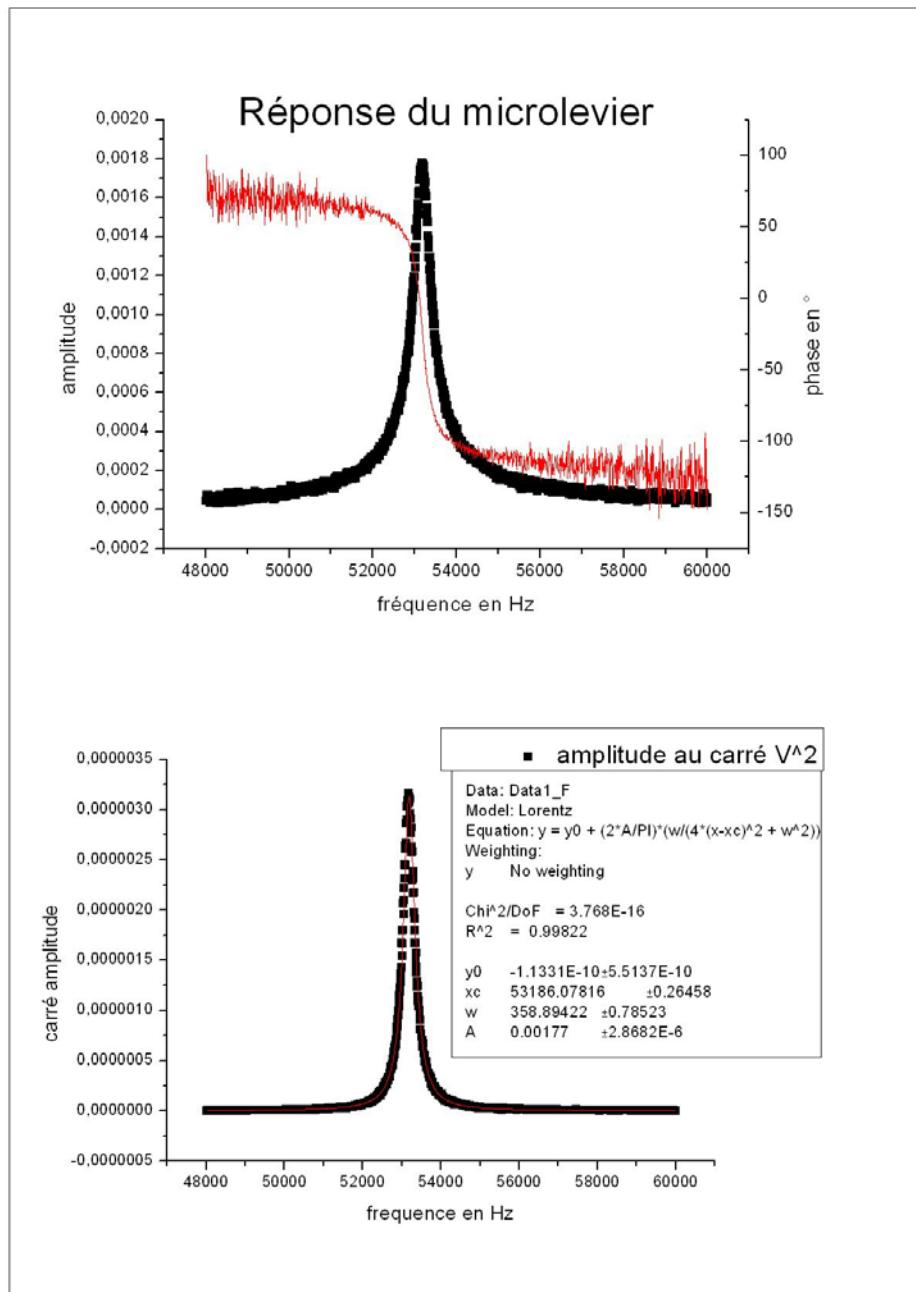
*X ray  
microbeam*



Lever position monitored  
Fabry Perot cavity:  
open space-compact system  
no external optical system

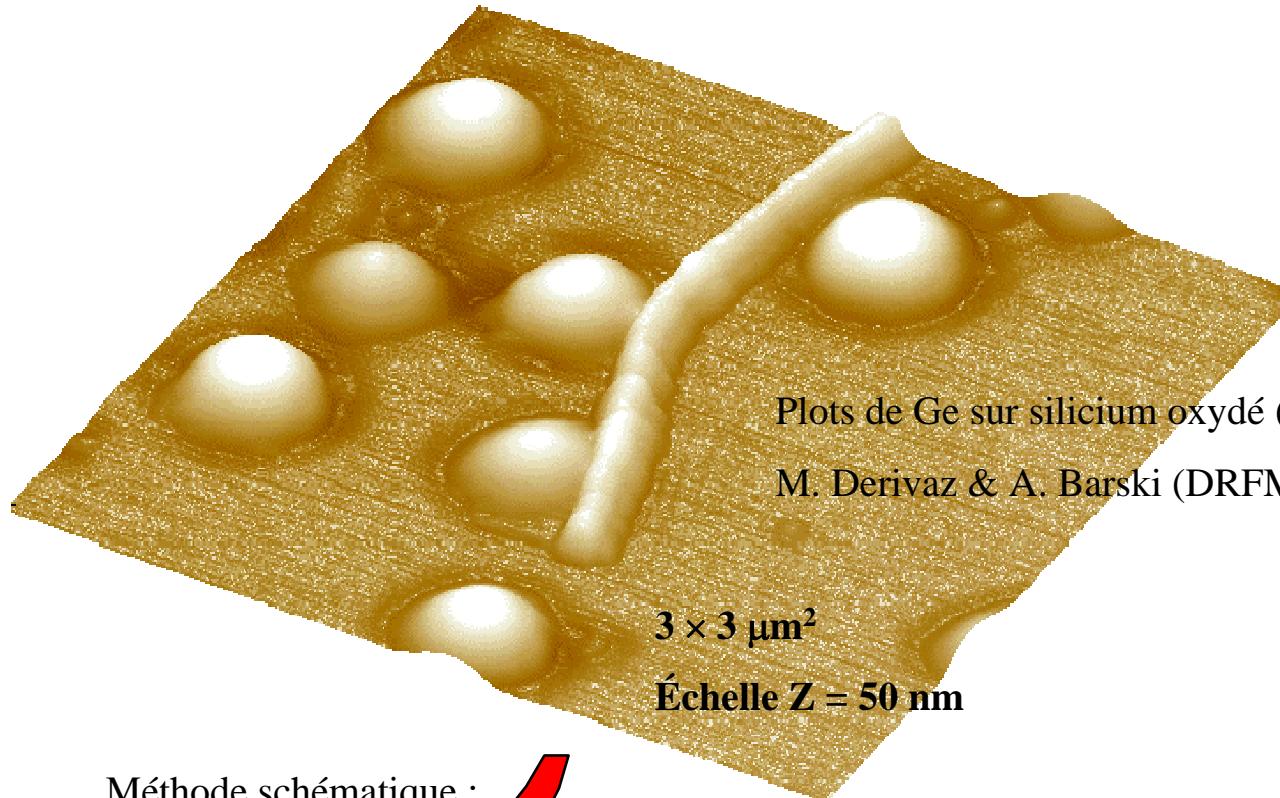


Coll. ESRF-LEPES-Spectro

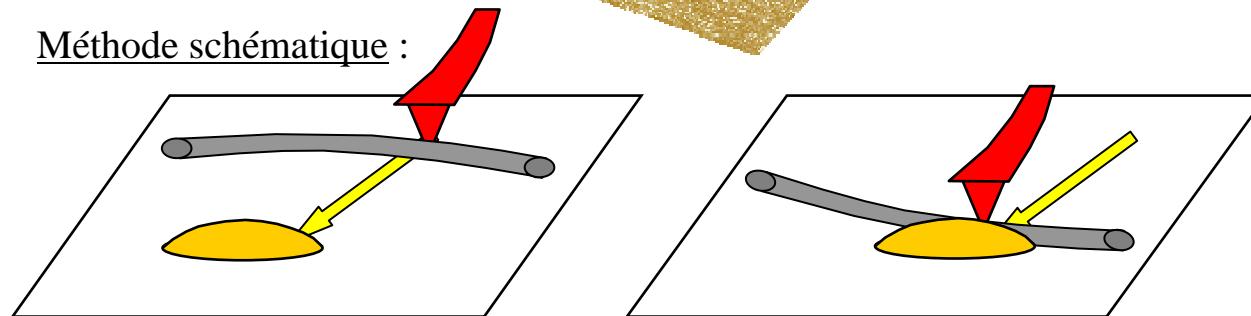


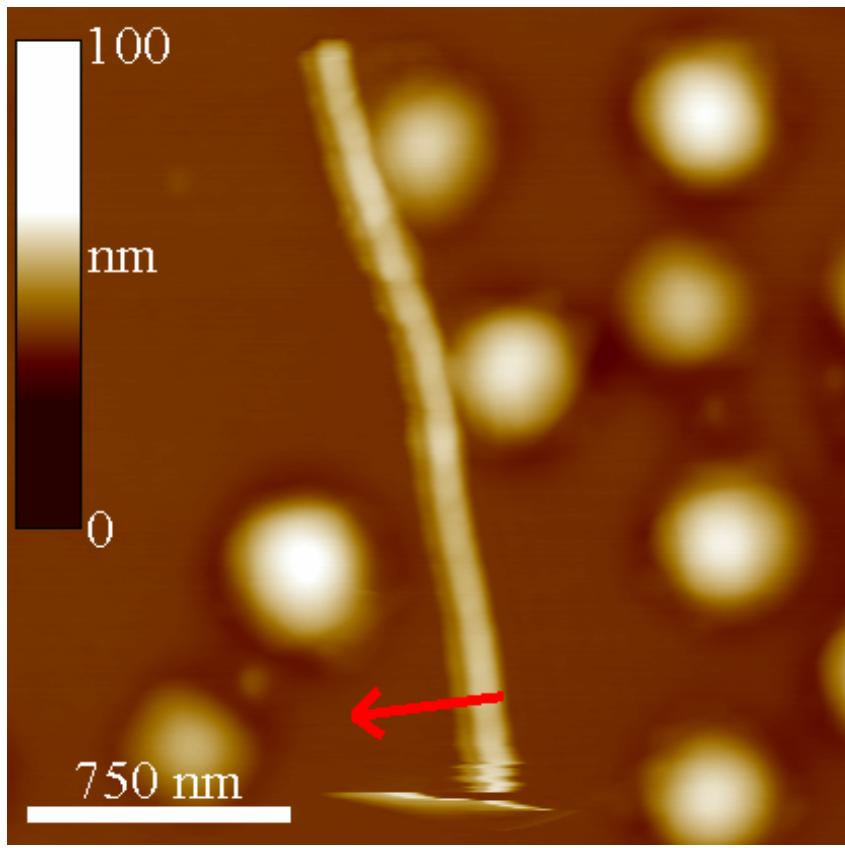
# *Nanomanipulation*

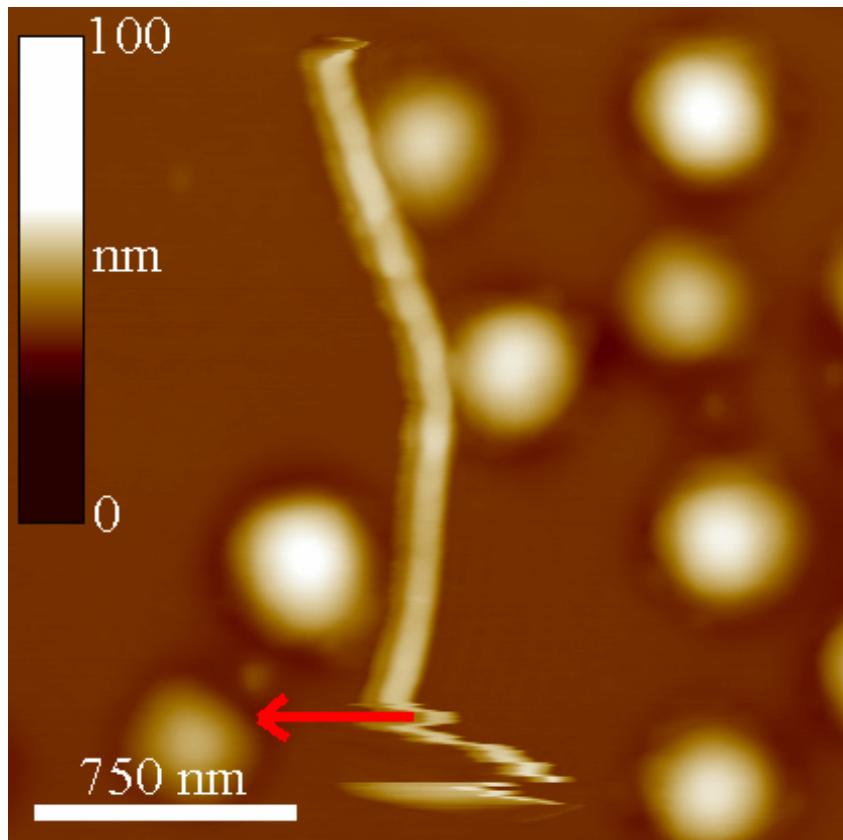
*real time in situ controlled deformation of a nanoobject*

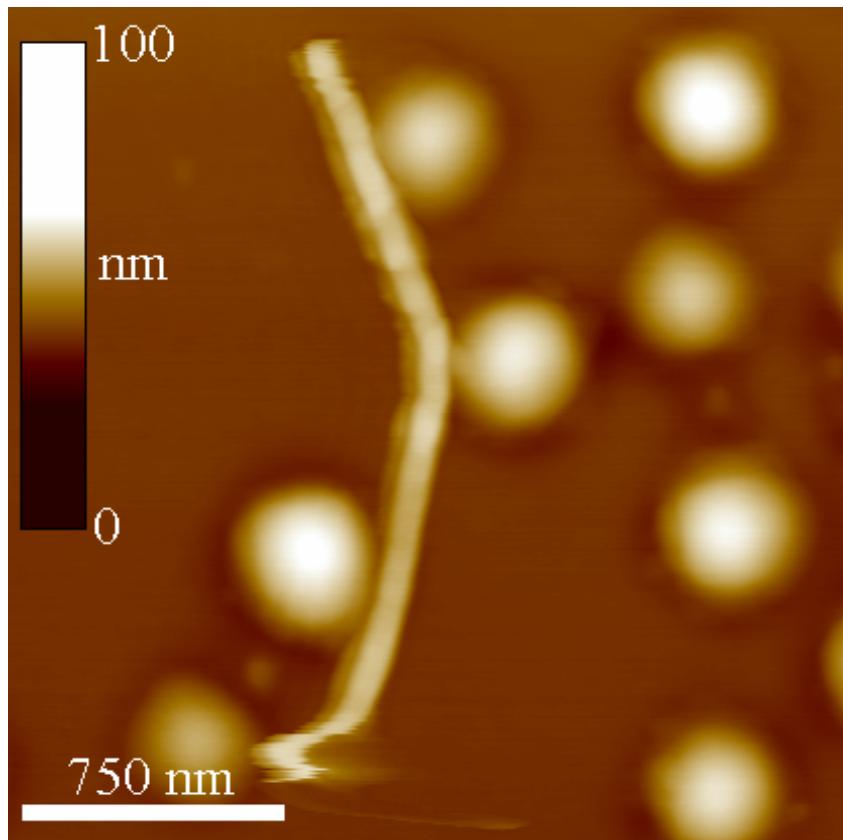


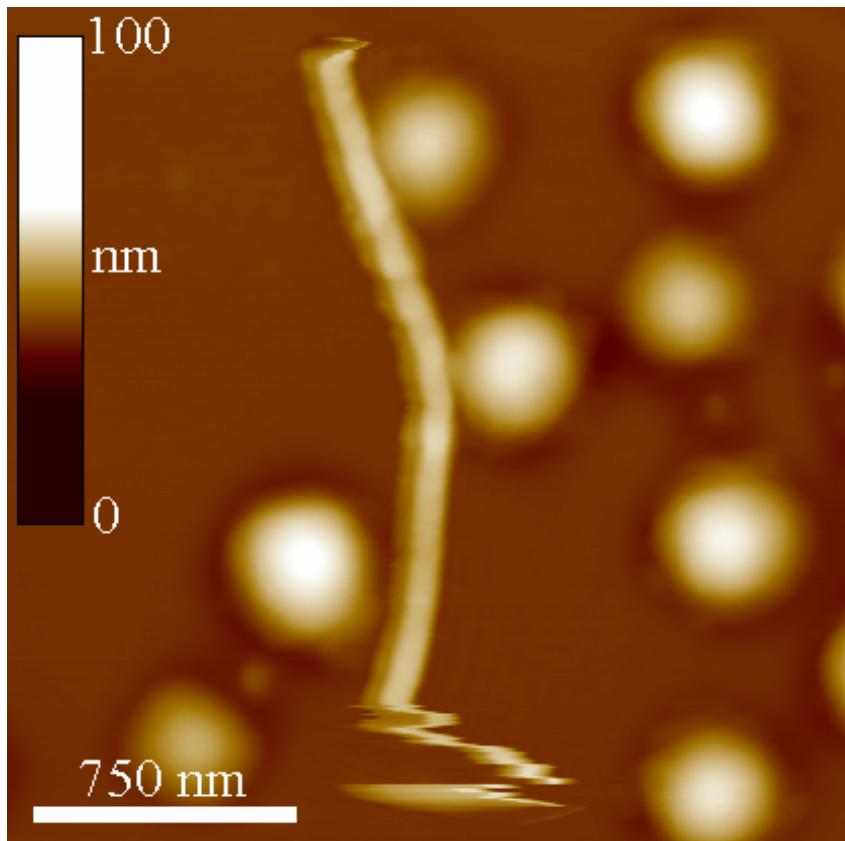
Méthode schématique :

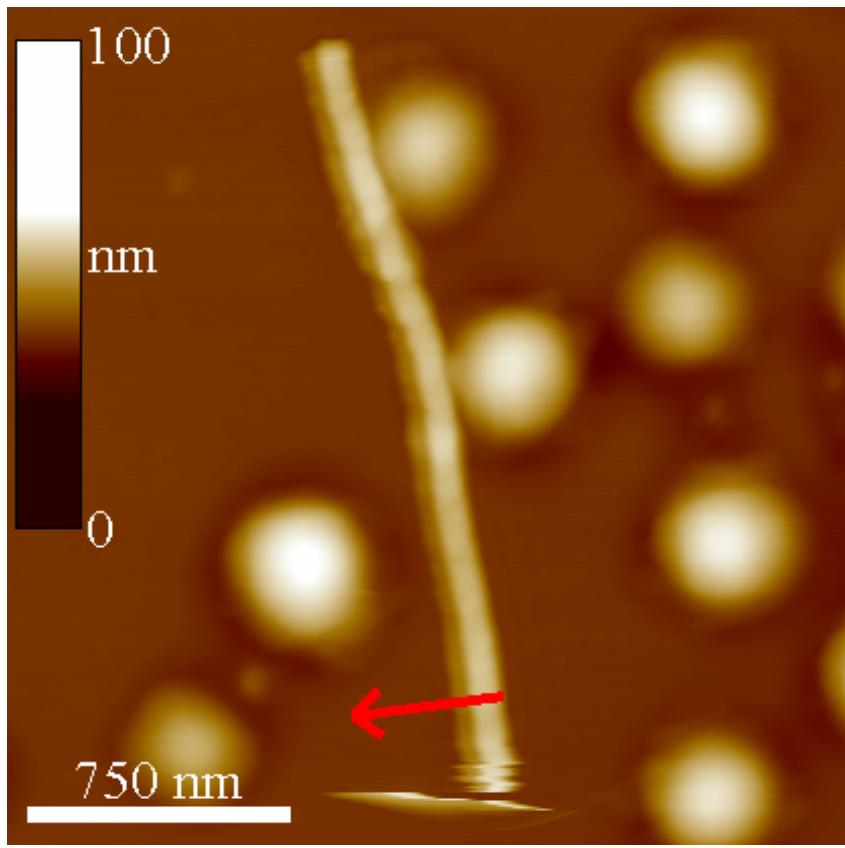


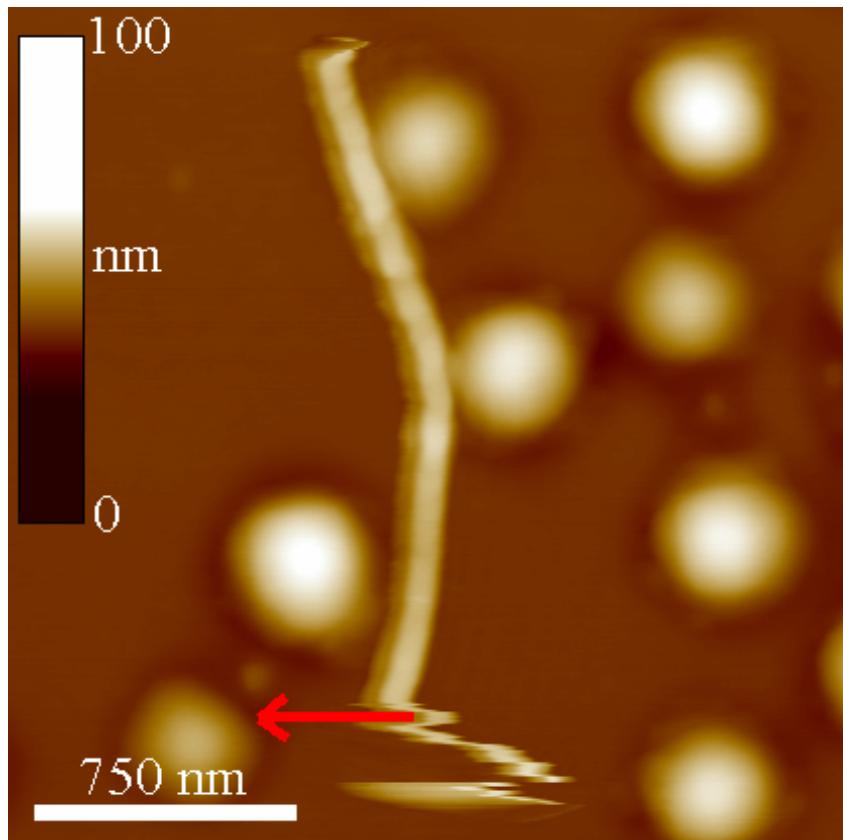


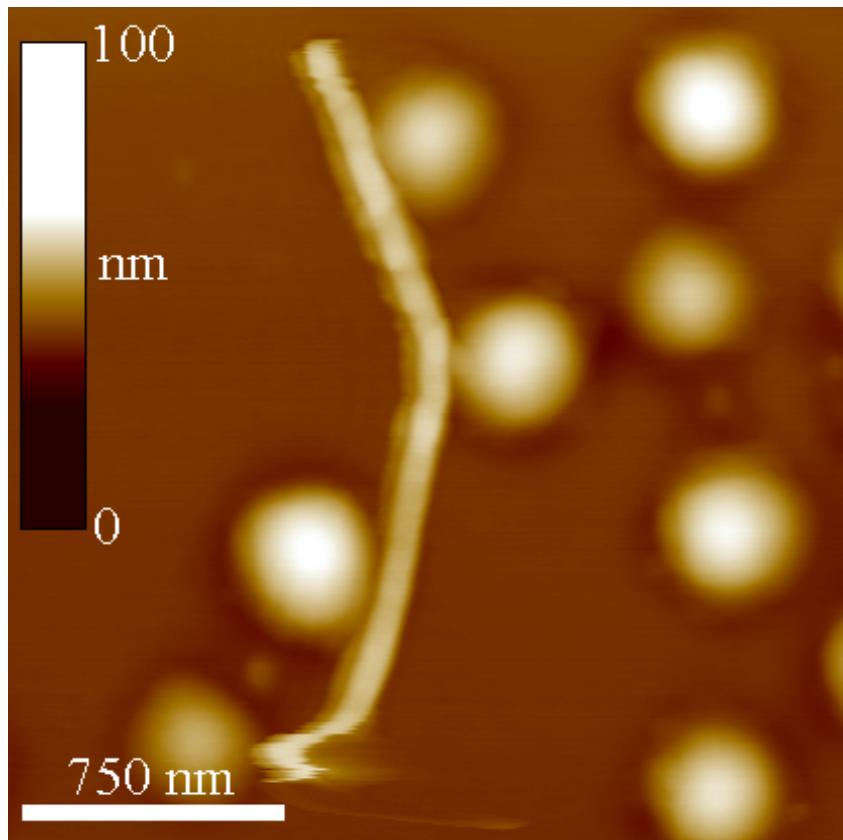


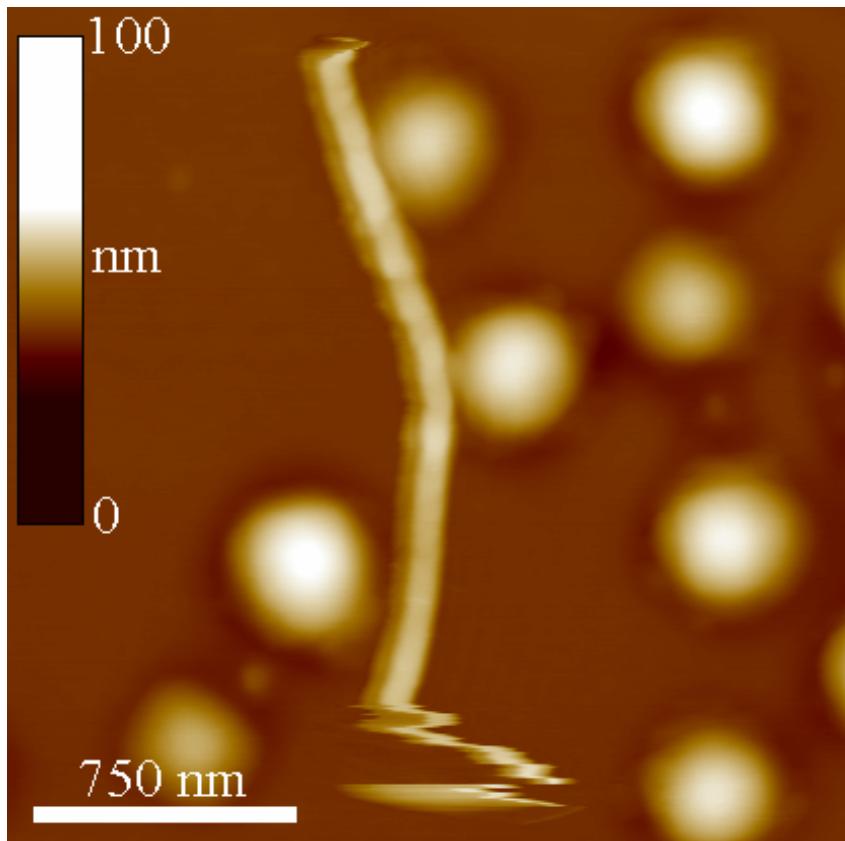


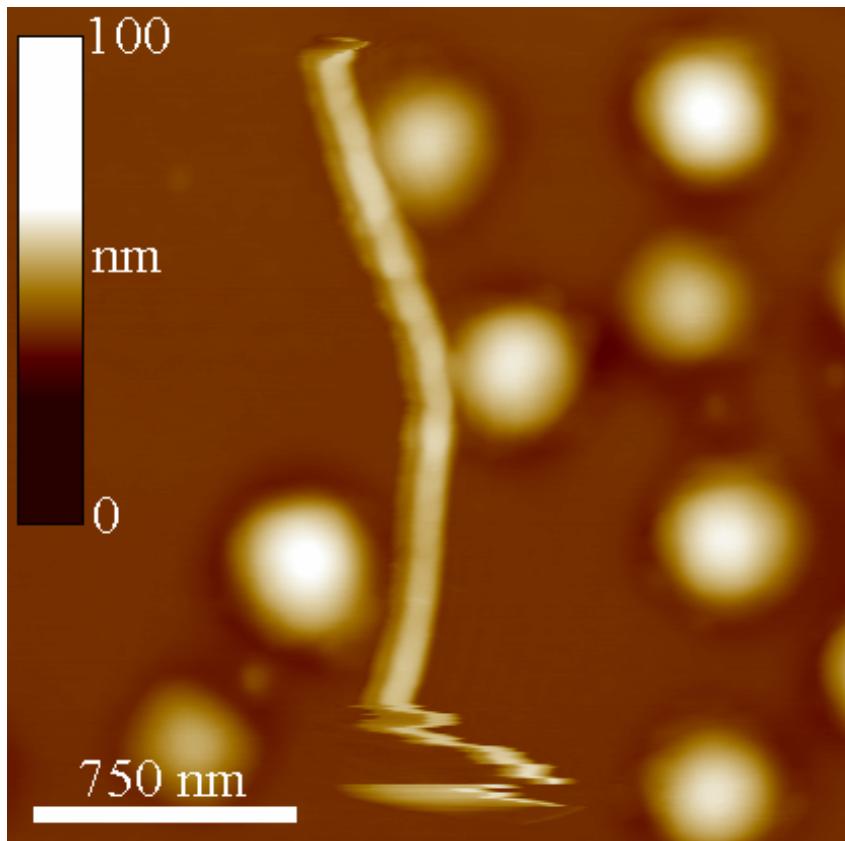




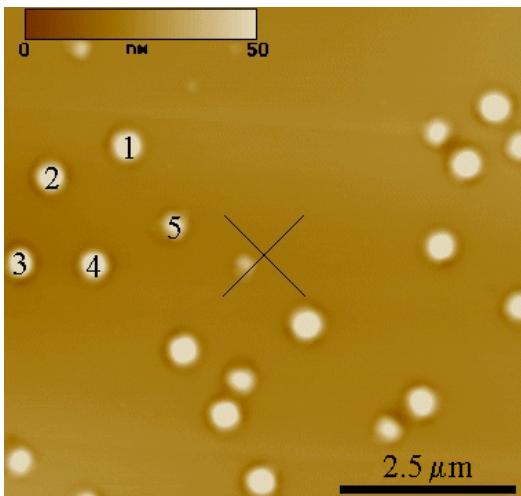
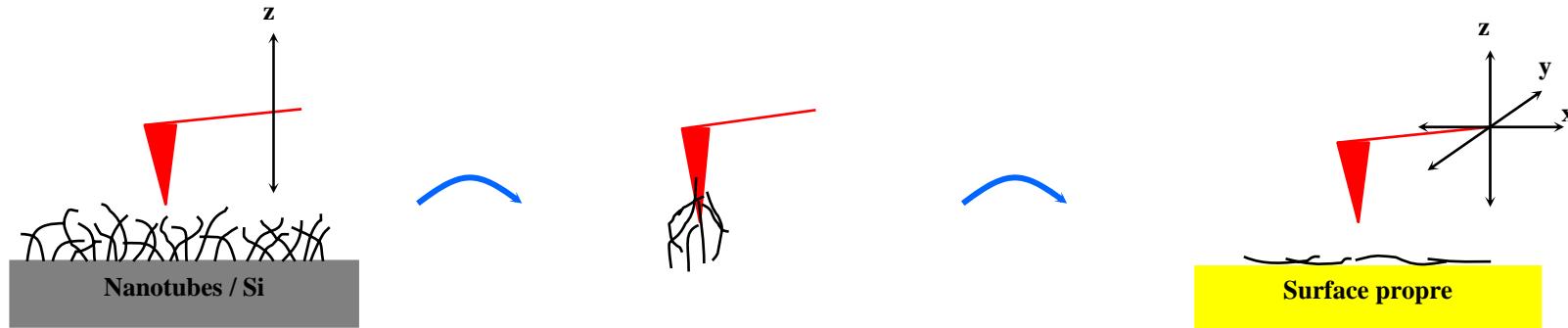




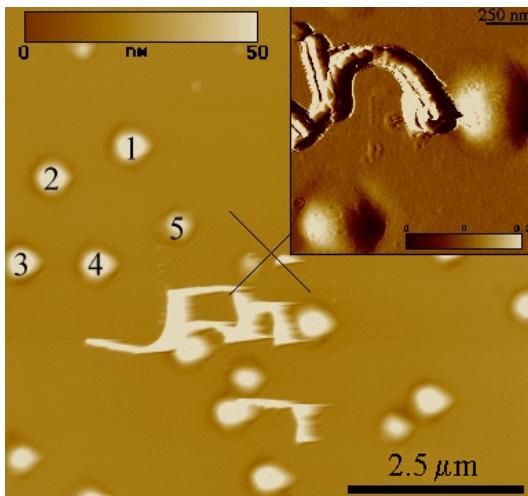




# TRANSPORT and ABSOLUTE nanoPOSITIONING of Carbon nanotubes



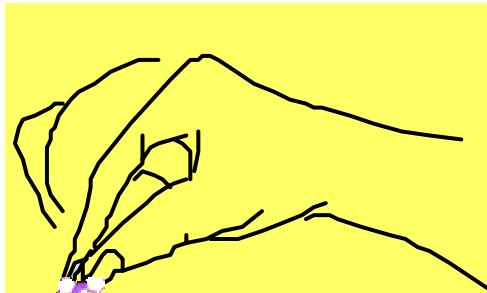
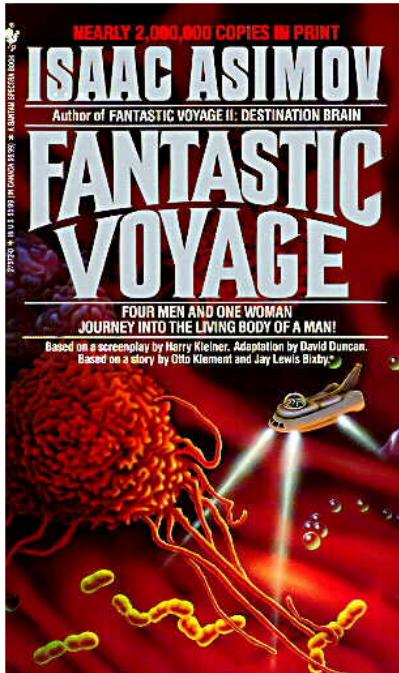
Before  
contact mode



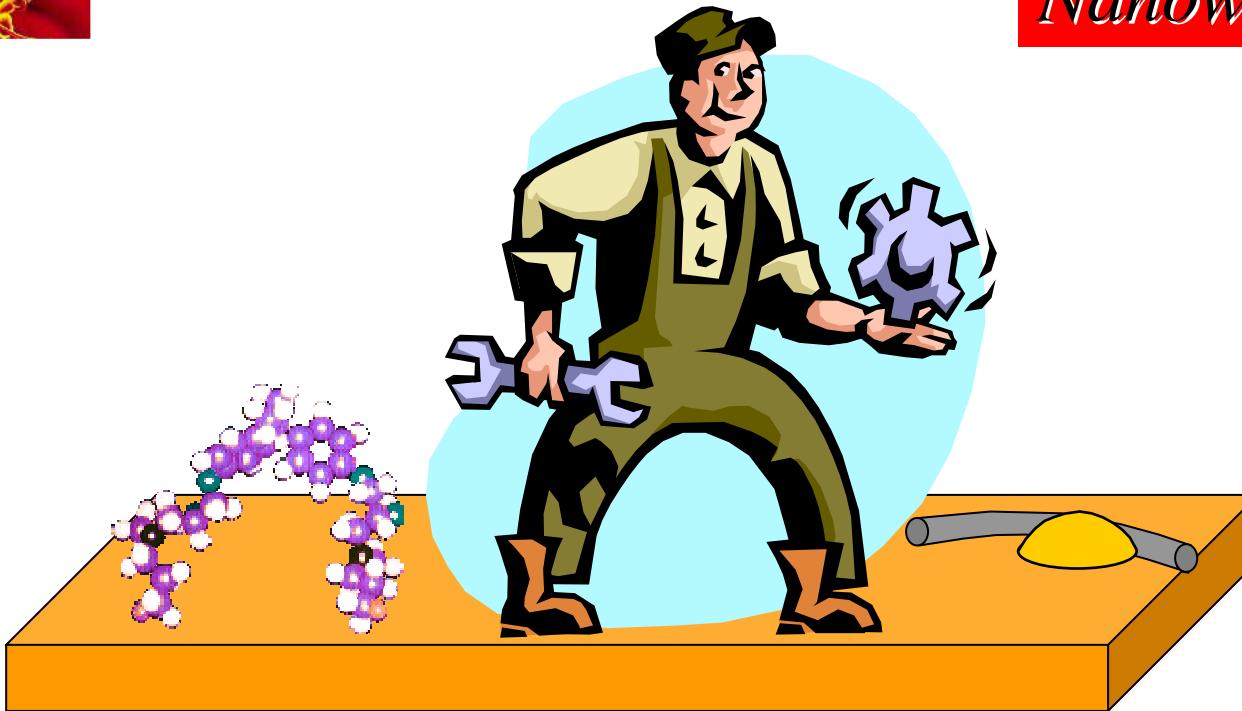
After  
non contact mode

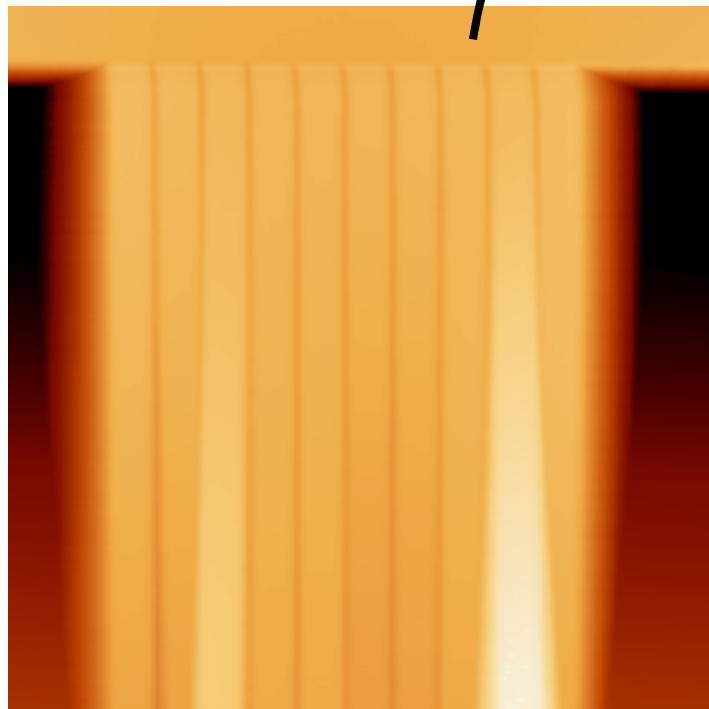
## Deposition

► Précision  $\approx 300$  nm

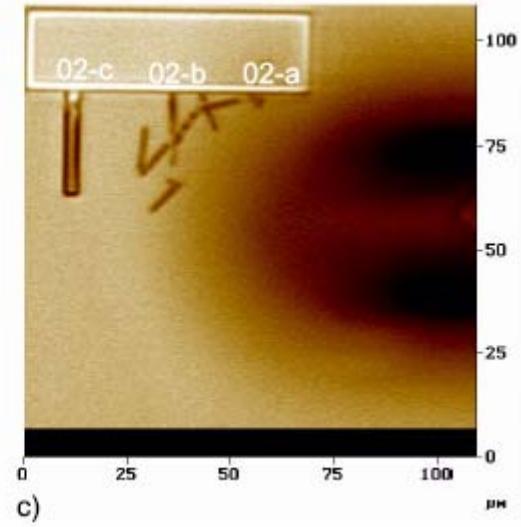
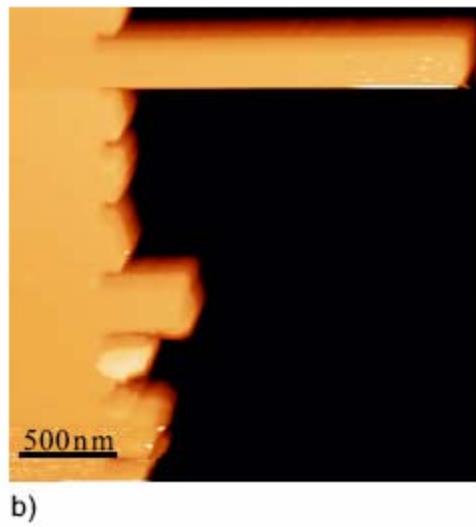


*Nanoworld*



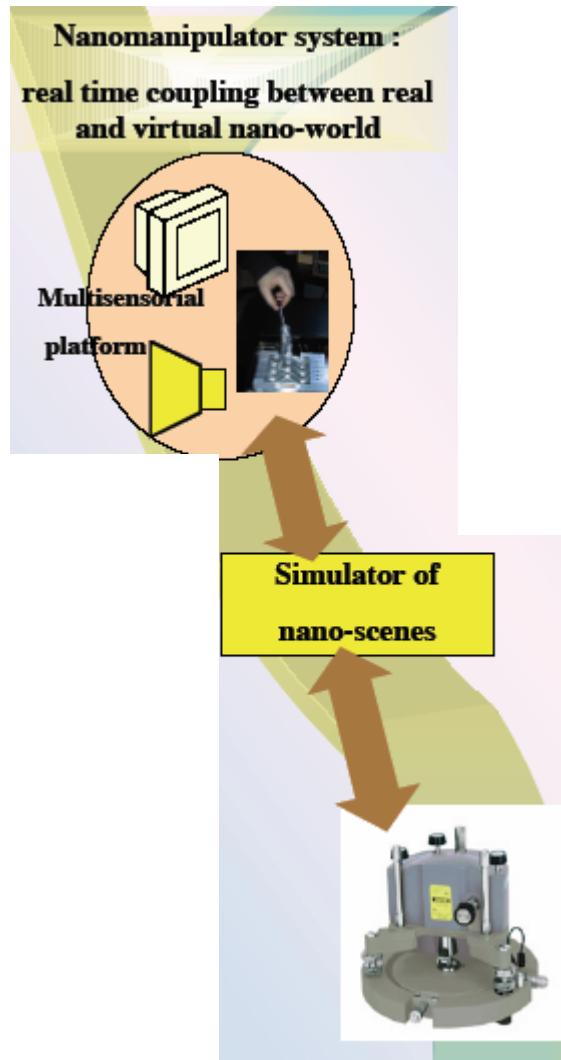


Careful AFM nanomanipulation  
of a LETI nanosystem

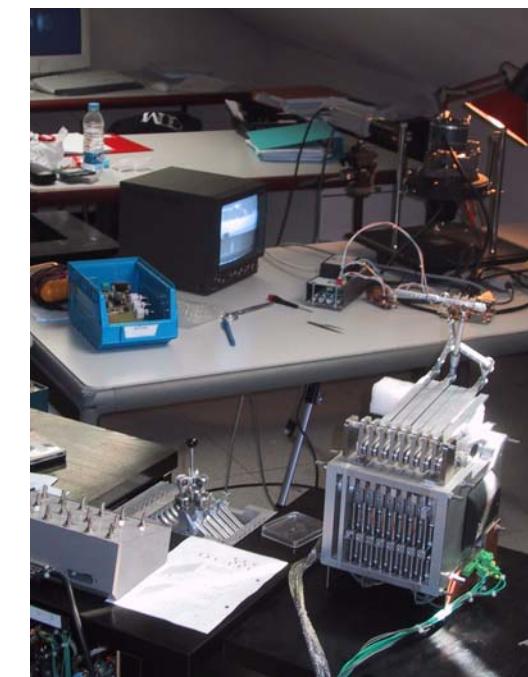
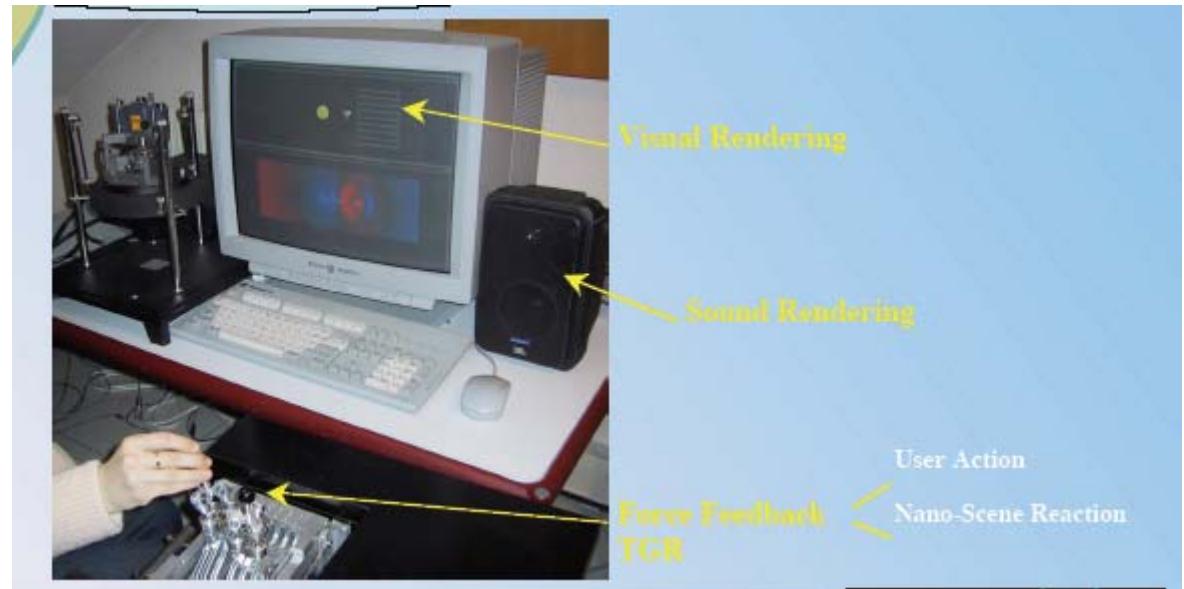


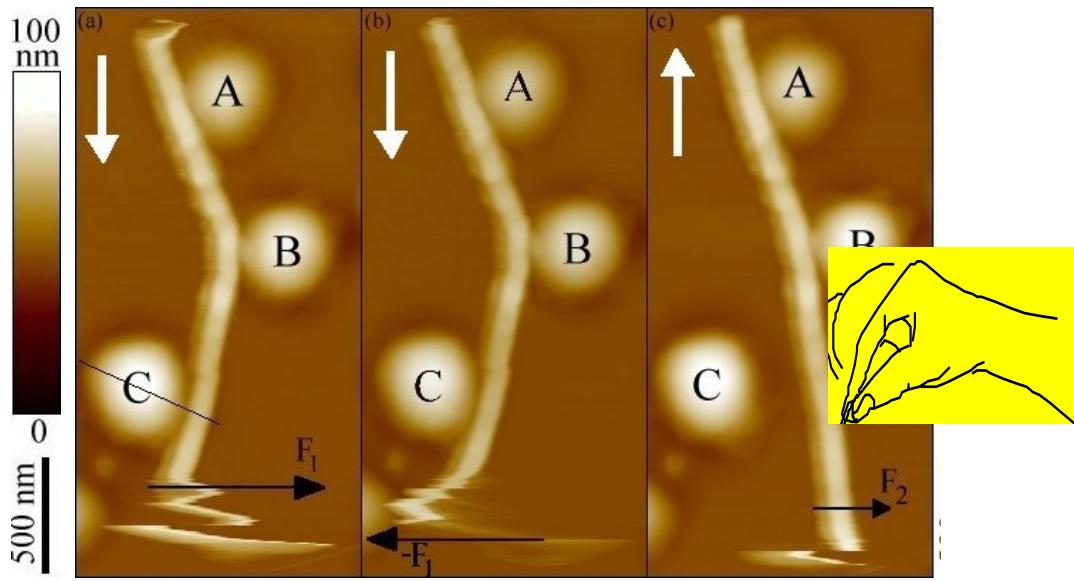
However....  
Life can be somewhat tricky !!!

# Direct human nanoobject link



Force amplification  $10^9$   
bandwidth 3kHz  
magnification of length  $10^7$   
nm to cm





Here the basic manipulation is:  
 - pushing- pulling -

*more is needed to truly manipulate  
 micro/nanosample*

*say object with size 100nm-1μm  
 and interaction control*

